

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Beng Ghee Tan
Serial No: 10/542,873
Filed: July 20, 2005
For: A Method for Detecting and Monitoring Wafer Probing Process
Instability
Confirmation No: 8349
Group Art Unit: 2829
Examiner: Roberto Velez
HDP Ref: 5731-000014/US/NP

April 23, 2007

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

AMENDMENT C UNDER 35 U.S.C. 1.312

Sir:

Please enter the following amendments into the record of the above-noted application under the provisions of 35 U.S.C. 1.312:

Amendments to the Specification, which begin on page 2 of this paper.

Remarks begin on page 3 of this paper.

Plase Enter

[Signature]

04/26/2007